



ISSYS Awarded Two Patents for New Microfluidic Device Designs

YPSILANTI, MI--(September 15, 2009) - Integrated Sensing Systems, Inc. (ISSYS) announced that the U.S. Patent Office has granted it utility patents (US 7,568,399) titled "Microfluidic Device" and (US 7,581,429) "Microfluidic Device and Method of Operation."

According to Doug Sparks, Executive VP of ISSYS, these patents describes new designs for microfluidic devices using resonating micromachined tubes. These sensor chips are used by ISSYS to produce Coriolis mass flow meters, density and chemical concentration sensors, drug infusion systems, fuel cell concentration sensors, and other devices. It complements other patents owned by ISSYS in the area of flow sensors and MEMS (MicroElectroMechanical Systems) devices. It provides new tube shapes that enable smaller chips size and hence lower cost product. This cost reduction in particular is of paramount importance for high-volume applications such as fuel cells, aviation fuel quality and drug delivery systems or any applications with disposable sensing parts. Also included in the claims are methods of combining active circuitry, often called ASICs – Application Specific Integrated Circuits- into the microfluidic chip via stacking or silicon MEMS integration.

Dr. Nader Najafi, ISSYS President and CEO, stated that, "These new patents and technology offers improved fluidic sensor and system designs. The basic technology is already seeing use in industrial and biomedical devices, as well as fuel cell systems. This reinforces the other ISSYS' patents on the design, packaging, fabrication, and application of microtube-based sensors, giving ISSYS comprehensive IP protection and offering a competitive barrier to market entry."

Company Background:

ISSYS is a leader in advanced MEMS technologies for industrial, medical devices, microfluidic and scientific analytical sensing applications. Founded in 1995, ISSYS is one of the oldest independent MEMS companies in the US. ISSYS operates a "full manufacturing under one roof," multi-million-dollar, state-of-the-art MEMS fabrication facility located near Ann Arbor, Michigan. An ISO 9001:2000 certified and ISO 13485:2003 (medical device manufacturing) qualified organization, ISSYS is a vertically integrated company dedicated to developing and manufacturing system-level products based on MEMS technology (MEMS Inside), please visit:<http://www.mems-issys.com/>

Doug Sparks
Executive Vice President
Integrated Sensing Systems, Inc.
391 Airport Industrial Dr.
Ypsilanti, MI 48198
(734) 547-9896 ext 119
Fax (734)547-9964
dsparks@mems-issys.com